IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Shiva Prakash

Title: Atomic Force Microscopy Measurements Of Contact Resistance And Current-

Dependent Stiction

Serial No. New - Divisional of Serial No. 10/202,439 filed 07/23/2002

Herewith Filing Date: Prior Art Unit: 2856

Prior Examiner R. Raevis

Atty Docket: 061450/0304607 (FID-101-D3)

MAIL STOP: Patent Applications Commissioner for Patents P O Box 1450 Alexandria, VA 22313-1450

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Date of Deposit: July 3, 2003

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INFORMATION DISCLOSURE STATEMENT

Applicant submits herewith patents, publications or other information of which Applicant is aware which are believed to be material to the examination of this application and in respect of which there may be a duty to disclose in accordance with 37 CFR 1.56.

The filing of this information disclosure statement shall not be construed as a representation that a search has been made (37 CFR 1.97(g)), nor as an admission that the information cited is, or is considered to be, material to patentability, nor an admission that no other material information exists. The filing of this information disclosure statement shall not be construed as an admission against interest in any manner. Notice of January 9, 1992, 1135 O.G. 13-25, at 25.

The references cited herein were cited in the parent application Serial No. 10/202,439 filed July 23, 2002, and therefore copies are not included.

> Respectfully submitted PILLSBURY WINTHROP LLP

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INFORMATION DISCLOSURE CITATION PTO-1449				Atty Docket: 061450/0304607 FID-101-D3		Serial No. to be assigned		
			Applicant: S. Prakash					
Submitted: July 3, 2003				Filing Date: Herewith		Prior Group Art Unit: 2856		
U.S. PATENT APPLICATIONS								
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME		CLASS	SUBCLASS	FILING DATE	
	5,723,981	03 Mar 1998	Hellemans et al.		324	719	06/25/9	96
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	5,763,768	06/1998	Henderson, et al.		73	105		
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	L	FORE	IGN PATI	ENT DOCUMENTS	L		L	-
EXAMINER'S					г		Transl	lation
INITIALS	PATENT NO.	DATE	1	COUNTRY	CLASS	SUBCLASS		
						+	Yes	No
	}							
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)								
De Wolf, et al. "Lateral and vertical dopant profiling in semiconductors by atomic force microscopy using conducting tops" (J. Vac. Sci. Tech. A 13(3), May/June 1995, pp. 1699-1704								
EXAMINER				DATE CONSIDERED				

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.